

RC-3003

300mm Robot Alignment Tool



Stop “eyeball” alignments! Brooks’ ALIGN™ series of alignment tools provide a fast, repeatable and highly accurate method of aligning your wafer handling equipment — from wafer sorters and inspection tools to cluster tools and equipment front ends. Increase your yield and throughput through more accurate alignments while saving up to 75% of the time required by “eyeball” alignments.

The RC-3003 Robotic Alignment Tool uses optical non-contact measurement sensors to analyze robotic motion. The motion of the wafer is characterized in slots 1-5 and 21-25 in five axes: X, Y, Z, RX, and RY. Using on-screen instructions and “real time” graphical displays, the technician can make accurate adjustments to the machine setup. Numerical readouts provide statistical analysis, while Pass/Warn/Fail labels allow for fast, simple inspection of robots.

- > RC-3003 shown with handheld computer

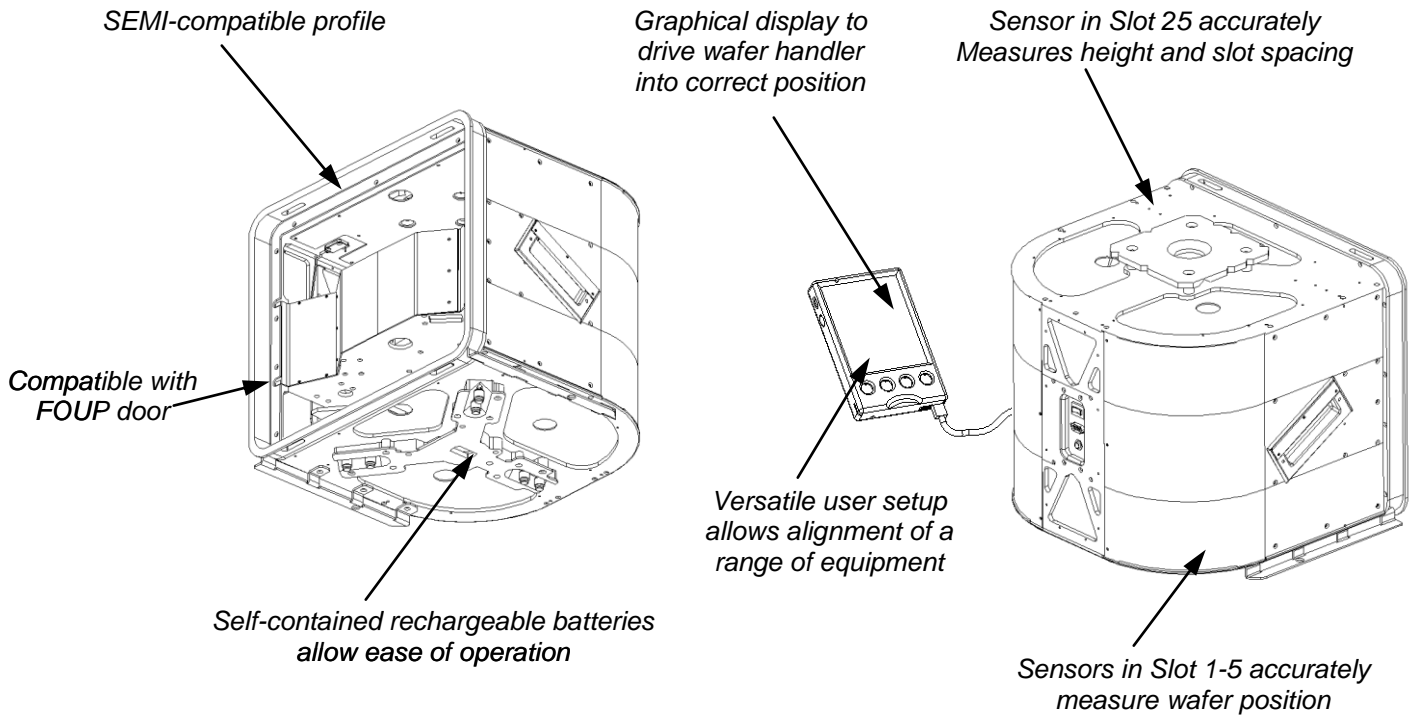


Features:

- > On-screen instructions provide intuitive operation.
- > “Real Time” Display screens provide fast and accurate robot setup and adjustments.
- > Optical non-contact measurement sensors analyze robotic motion.
- > Wafer motion is characterized in 5 degrees of freedom: X, Y, Z, RX, & RY.
- > Compatible with 5-finger end effectors.
- > Measures a wafer in slots 1-5 and 21-25
- > Bubble screen provides intuitive display of platform or wafer pitch and roll.

Benefits:

- > Improve wafer handling.
- > Save maintenance time.
- > Reduce MTTR.
- > Increase MTBF.
- > Reduce particulation and increase yield.
- > Eliminate wafer scratching.



Specifications

DESIGN

- Non-subjective and highly repeatable sensors replace the traditional “eyeball” alignment
- Full 5-axis alignment in slot 1-5 and 21-25.
- Intuitive display guides operator to correct robot position for X, Y, Z, rX, and rY (height, rotation, extension, pitch, and roll)
- Easy to read real-time display allows platform leveling
- Can be used to check or teach alignment
- Self-contained unit is battery operated
- Windows® CE-based controller provides power and flexibility
- On-board data logging capability

COMPATIBILITY

- SEMI-compatible profile assures interface with nearly all wafer handling equipment.
- Drop-in replacement for FOUNDRY in most equipment.

OTHER

Power required: 110/220-volt charger (included)

Part size: 355mm x 455mm x 355mm (14" x 18" x 14")

Part weight: 10 kg (22 lb)

